

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Jiutao Li et al.

Application No.: 10/712,106

Confirmation No.: 8216

Filed: November 14, 2003

Art Unit: 1753

For: SILVER SELENIDE SPUTTERED FILMS  
AND METHOD AND APPARATUS FOR  
CONTROLLING DEFECT FORMATION IN  
SILVER SELENIDE SPUTTERED FILMS

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Examiner: R. G. McDonald

OK TO ENTER: /RM/

07/08/2008

**AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Office Action dated March 28, 2008, finally rejecting claims 1-84, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 15 of this paper.